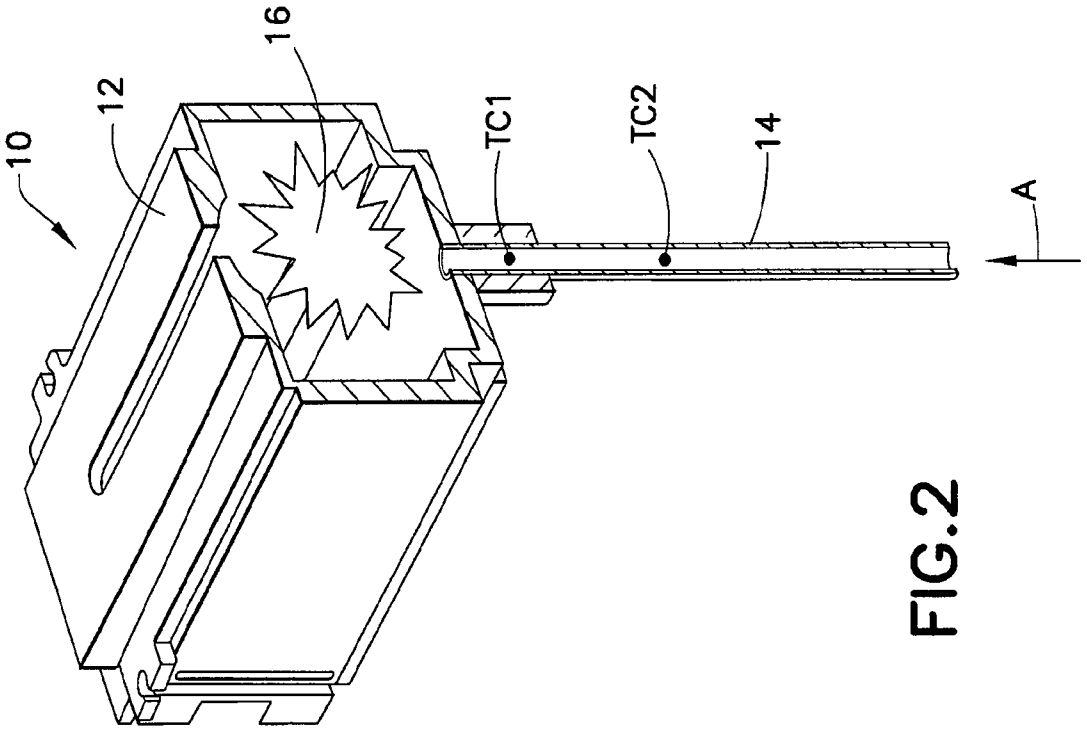


FIG.2

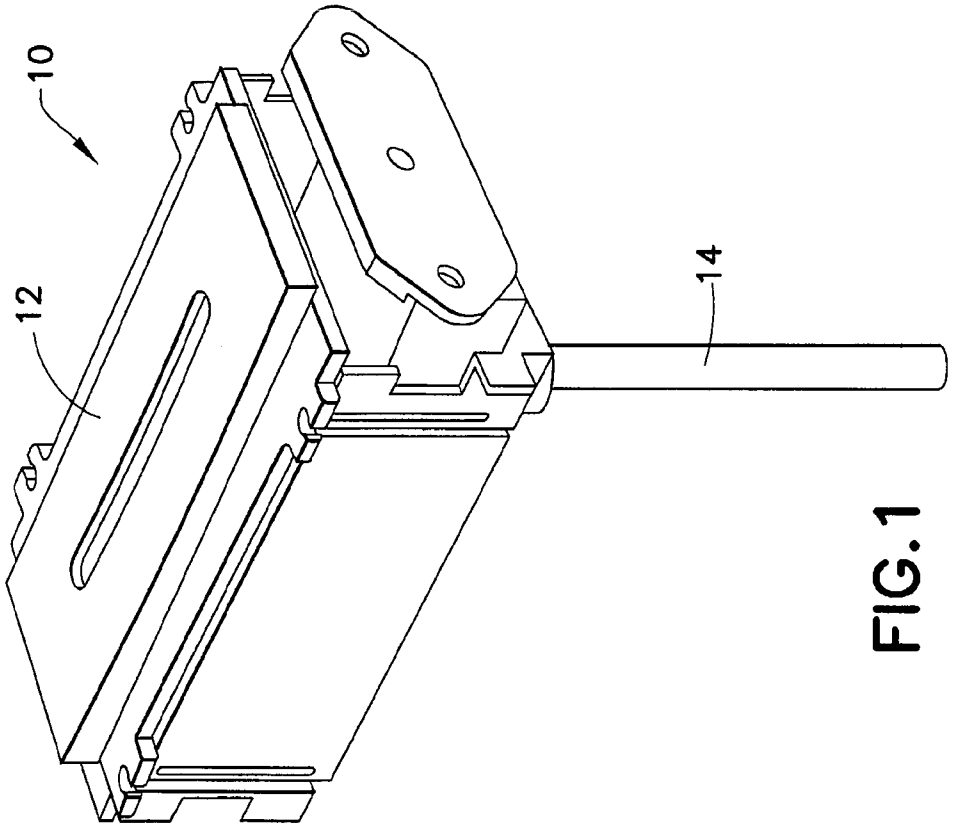


FIG.1

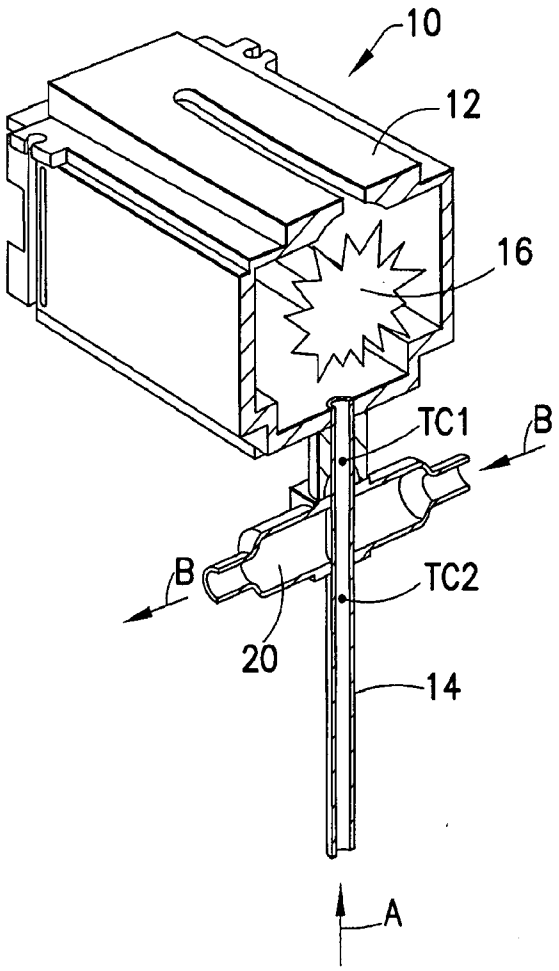


FIG.3

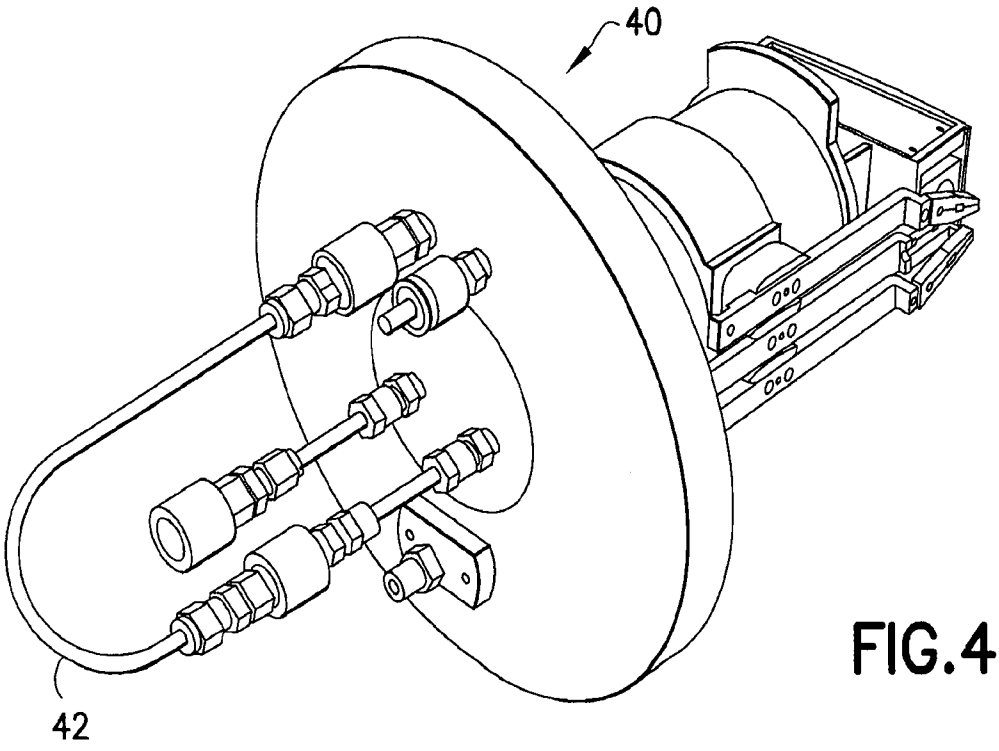


FIG.4

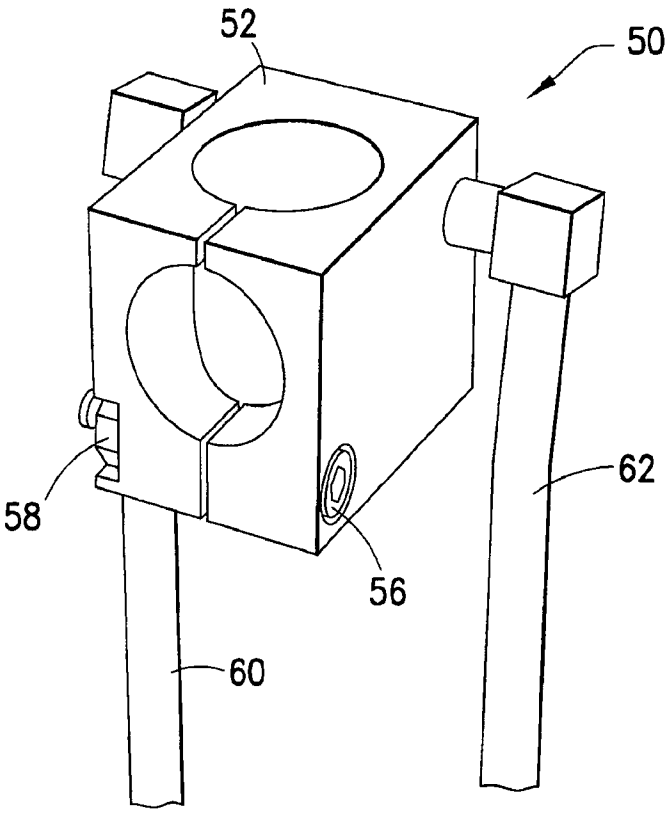


FIG.5

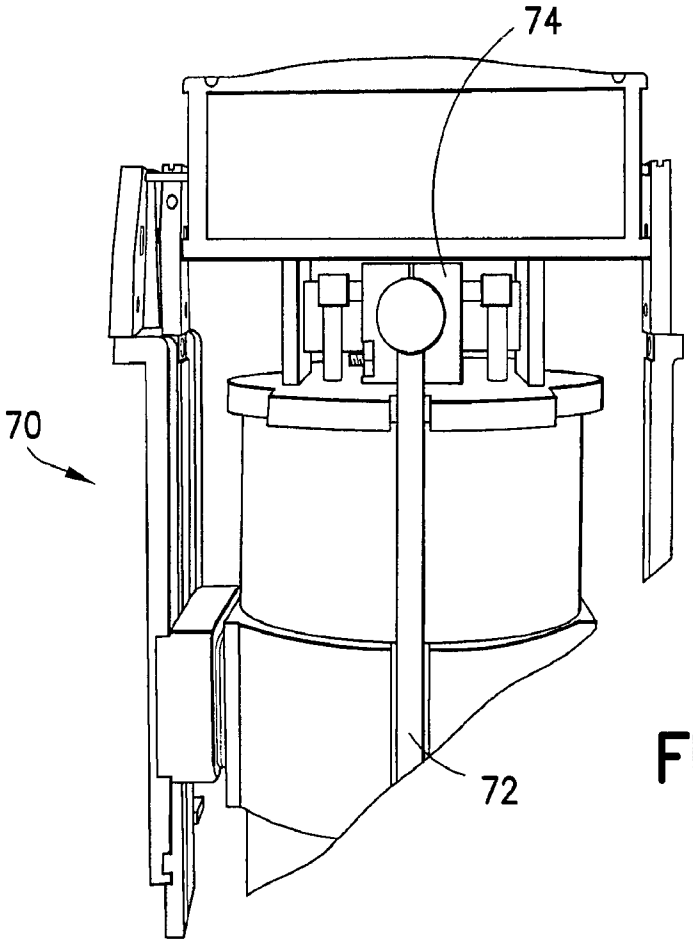


FIG.6

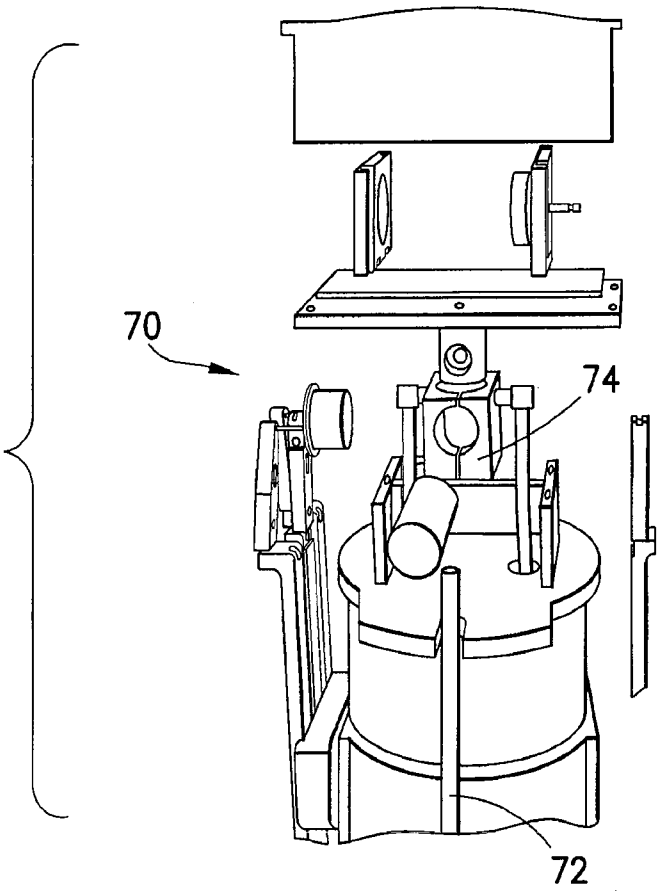


FIG.7

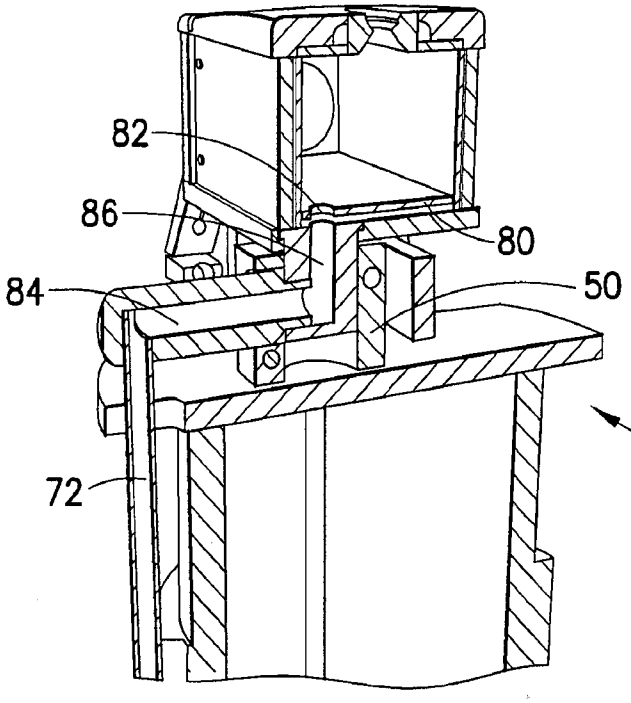


FIG.8

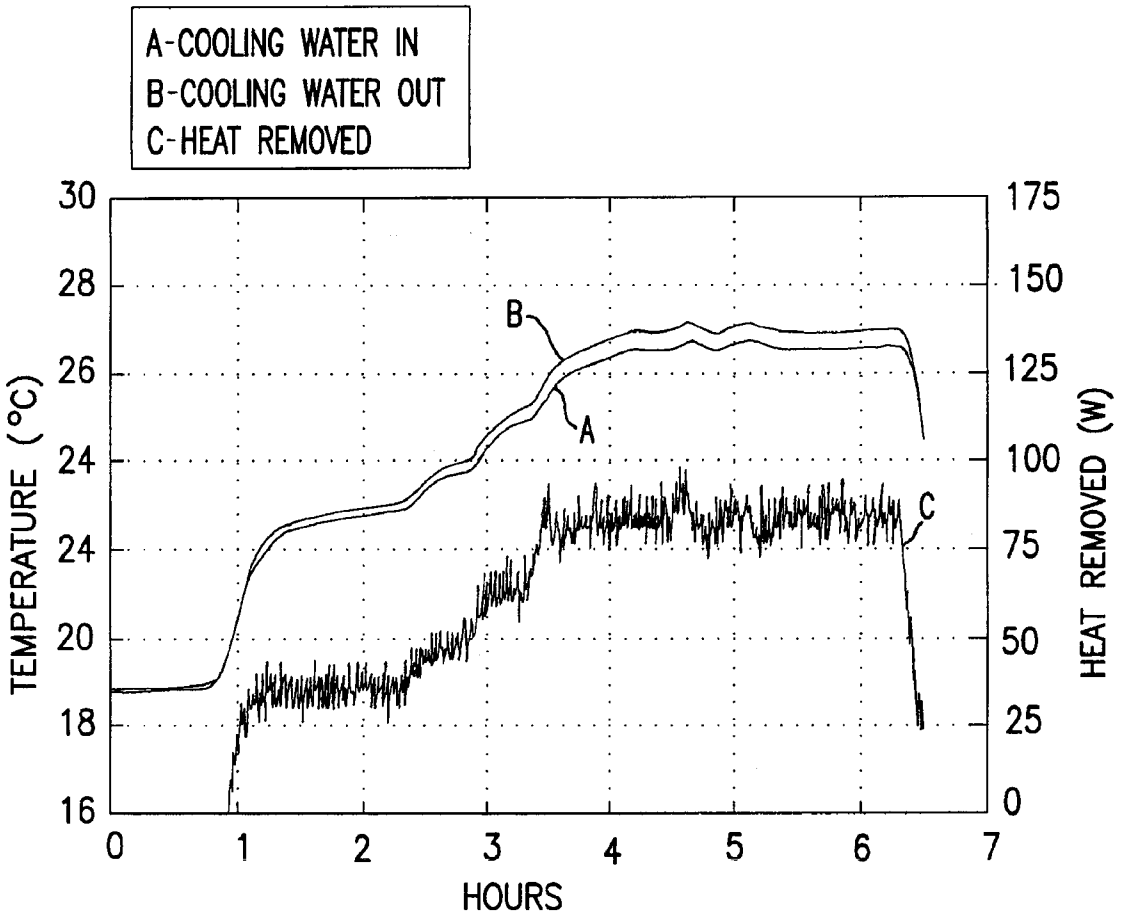


FIG.9

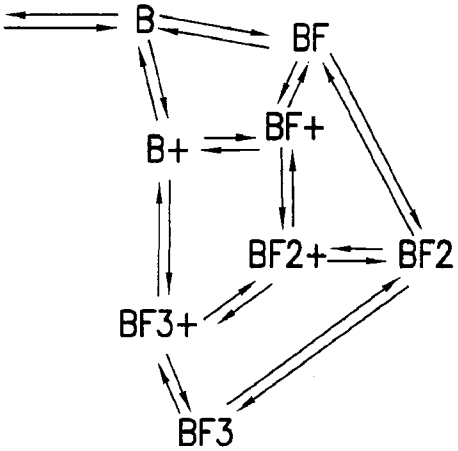


FIG.10

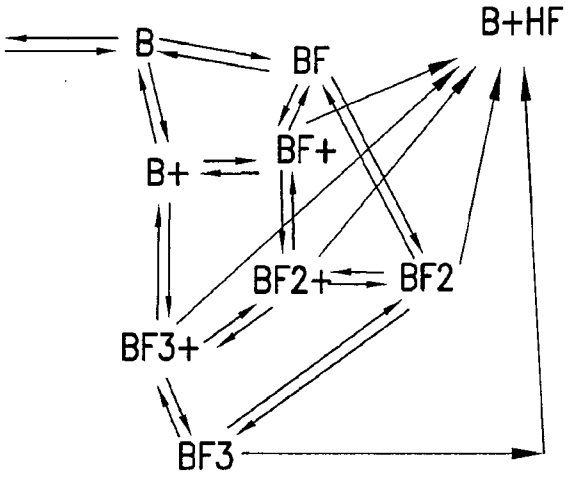


FIG.11

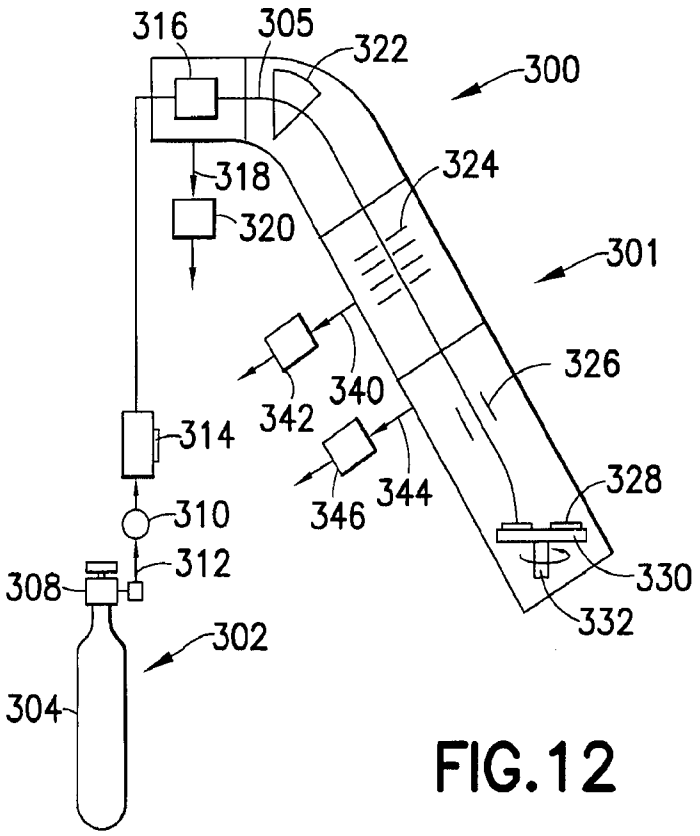

316
305
322
300
318
320
324
301
326
340
342
314
344
346
328
310
330
312
308
332
302
304

FIG.12

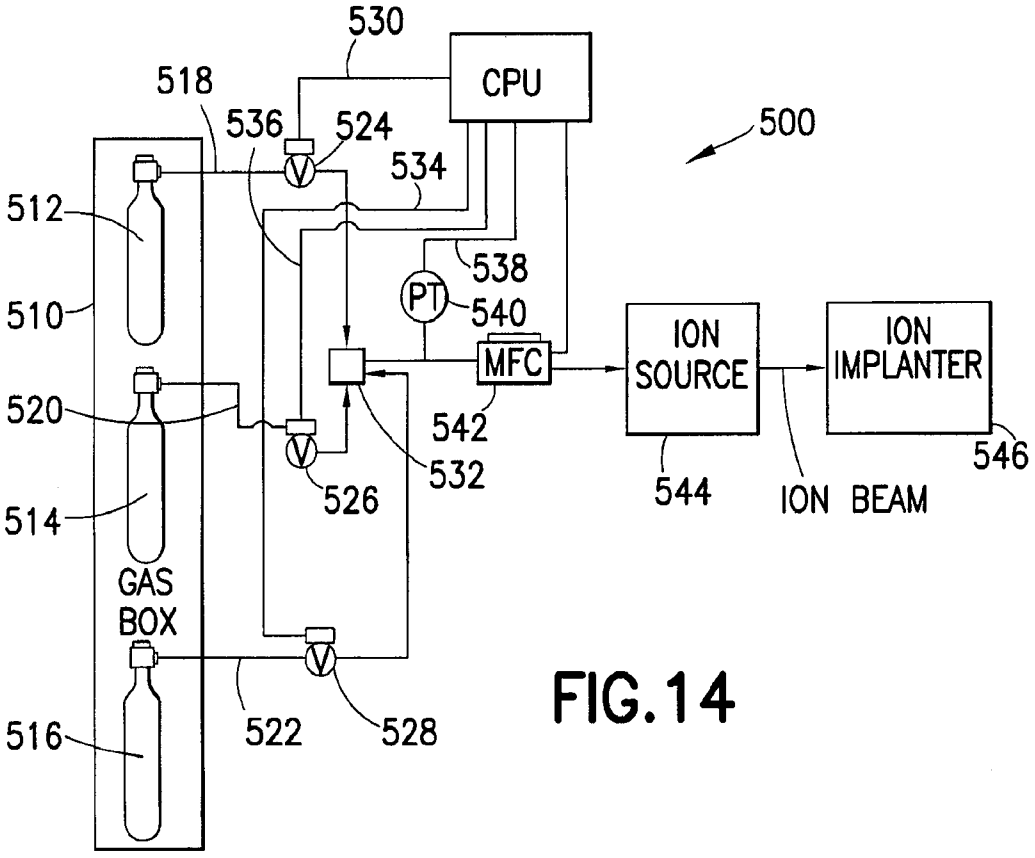

530
CPU
518
536
524
500
534
512
538
PT
540
510
ION SOURCE
ION IMPLANTER
MFC
520
542
532
526
546
544
514
ION BEAM
GAS BOX
516
522
528

FIG.14

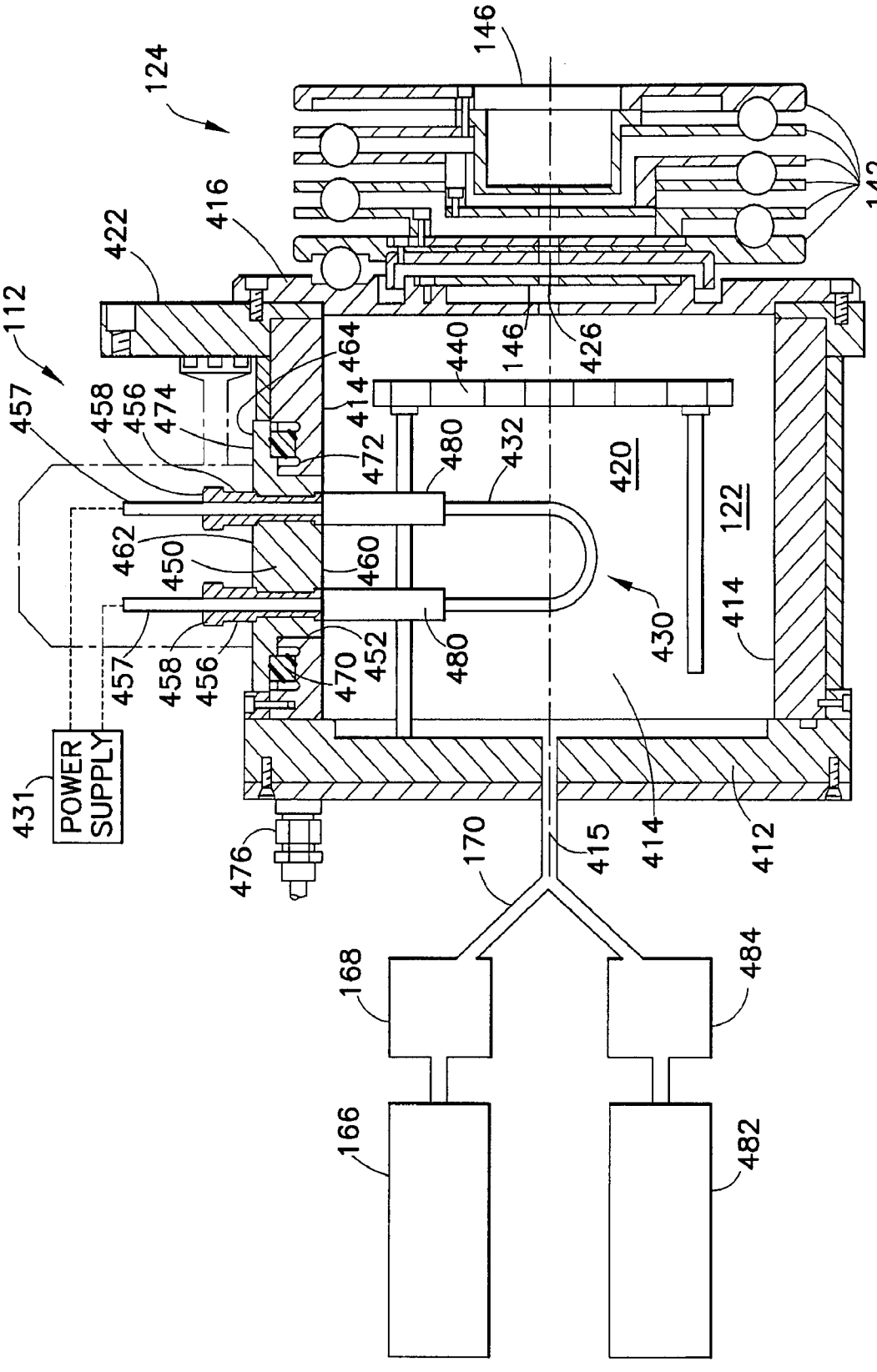

146
124
142
416
422
112
457
458
456
474
464
414
440
146
426
472
480
432
420
122
462
450
460
430
414
452
470
480
457
458
456
POWER SUPPLY
431
476
170
415
414
412
168
484
166
482

FIG.13

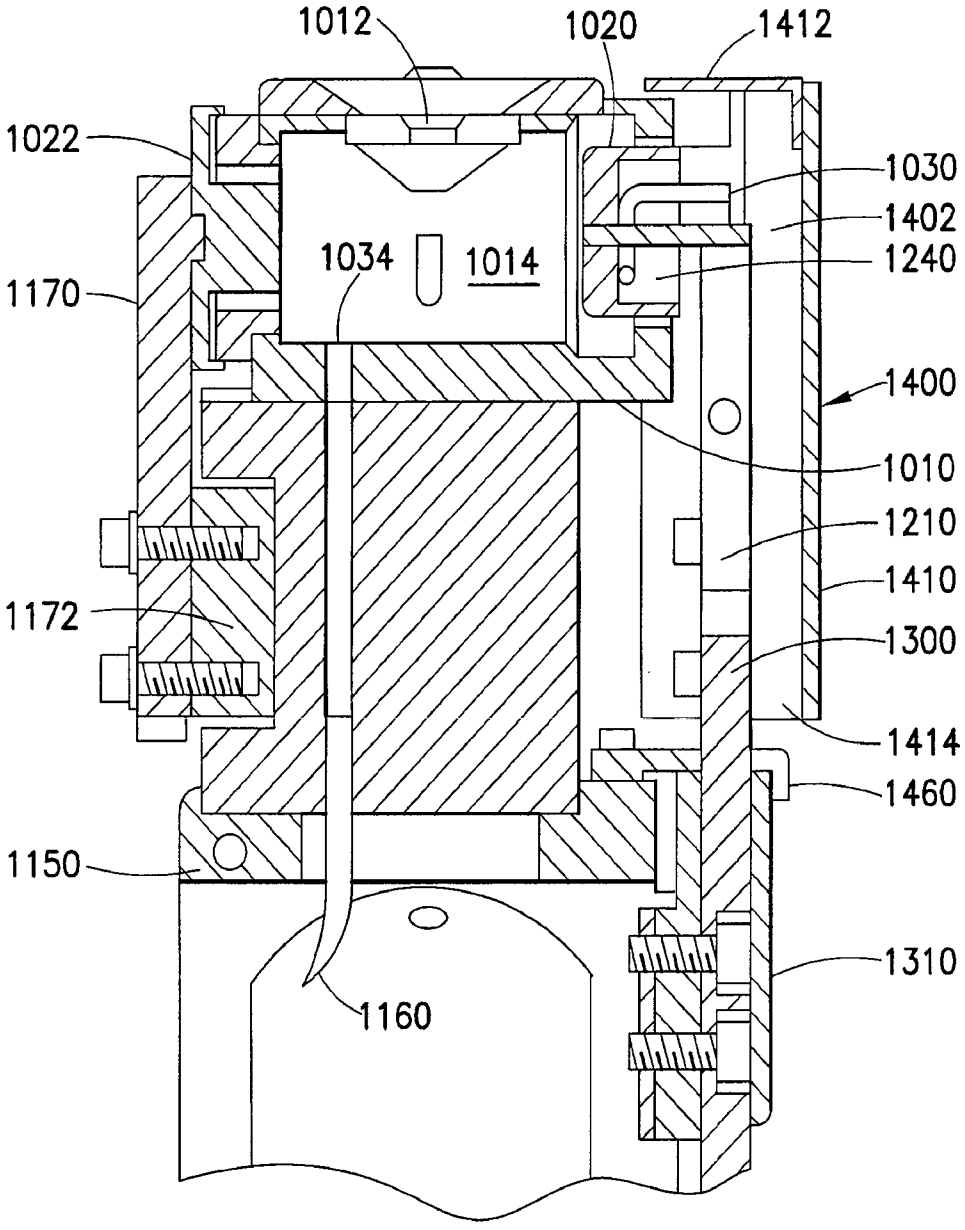

1012
1020
1412
1022
1030
1402
1034
1014
1240
1170
1400
1010
1210
1410
1172
1300
1414
1460
1150
1310
1160

FIG.15

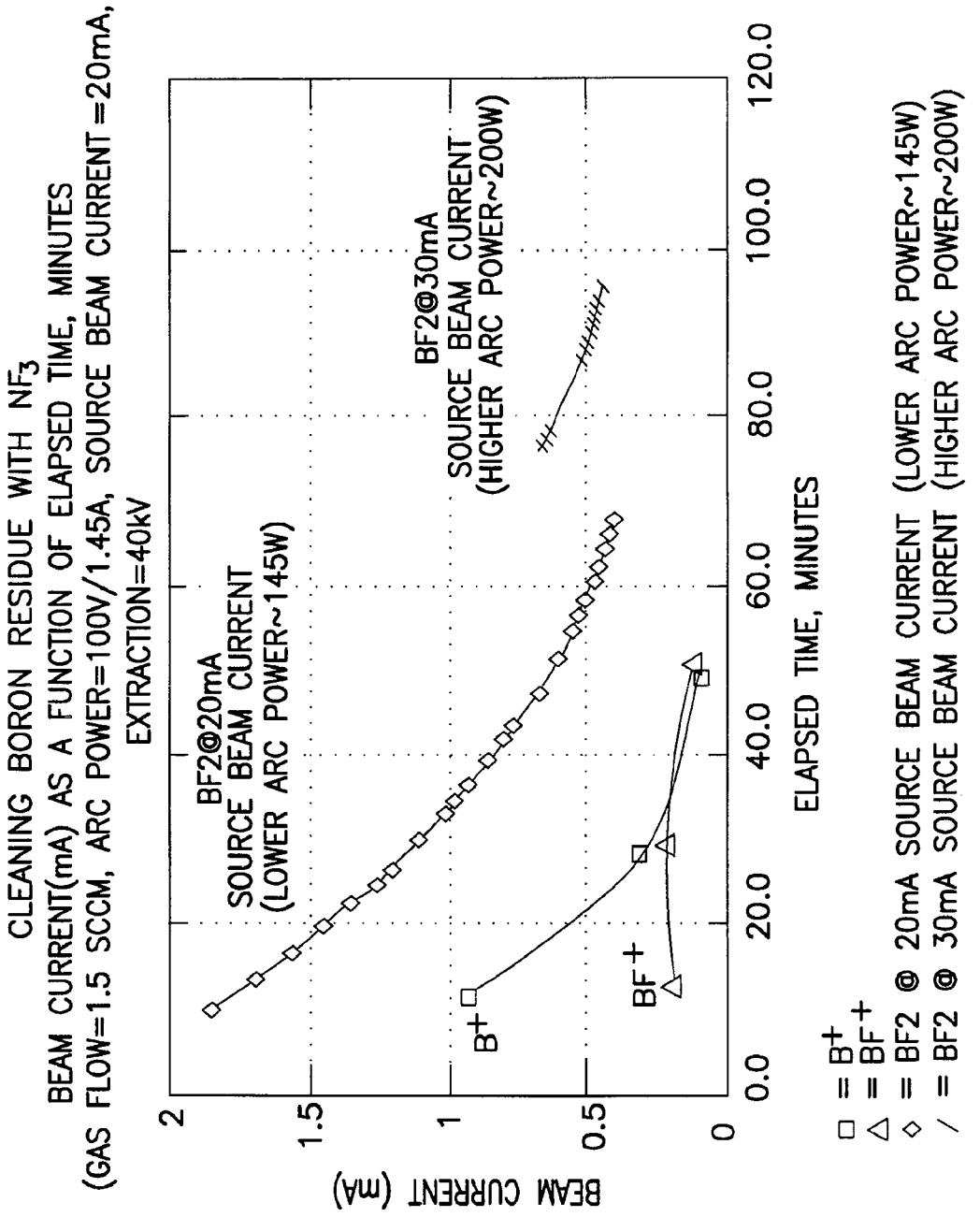

CLEANING BORON RESIDUE WITH NF3
BEAM CURRENT(mA) AS A FUNCTION OF ELAPSED TIME, MINUTES
(GAS FLOW=1.5 SCCM, ARC POWER=100V/1.45A, SOURCE BEAM CURRENT =20mA,
EXTRACTION=40kV
BF2@20mA
SOURCE BEAM CURRENT
(LOWER ARC POWER~145W)
BF2@30mA
SOURCE BEAM CURRENT
(HIGHER ARC POWER~200W)
B+
BF+
BEAM CURRENT (mA)
2
1.5
1
0.5
0
0.0
20.0
40.0
60.0
80.0
100.0
120.0
ELAPSED TIME, MINUTES
□ = B+
△ = BF+
◇ = BF2 @ 20mA SOURCE BEAM CURRENT (LOWER ARC POWER~145W)
/ = BF2 @ 30mA SOURCE BEAM CURRENT (HIGHER ARC POWER~200W)

FIG16